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Attorney Docket No. UMC-96-279 CON
Client Matter No. 81848.0016.001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No. 09/546,174

Application of: LIU, Chih-Chien *et al*

Filed: April 11, 2000

Art Unit: 1711

Examiner: SERGENT, R.A.

Attorney Docket No. UMC-96-279 CON

For: HIGH DENSITY PLASMA CHEMICAL
VAPOR DEPOSITION PROCESS

Confirmation No.: 4793

Customer No.: **25235**

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AMENDMENT AND RESPONSE UNDER 37 C.F.R. § 1.113

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

A final Office Action was mailed in the above case June 4, 2003. Please reconsider the case in light of the following remarks.

Amendments to the Claims are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 9 of this paper.